

Supplement 1 Jaffal M et al., *Topographic Area Selective Deposition: a comparison between PEALD/ALE and PEALD/sputtering approaches*

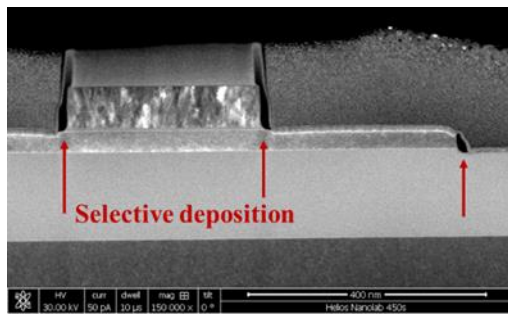


Figure 1 – TEM image of selective Ta₂O₅ deposition on sidewalls of raised 3D structures using PEALD + Ar⁺ sputtering super-cycle process

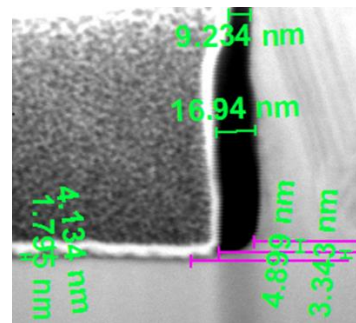


Figure 2 – Zoom of Figure 1 at the lower corner of raised 3D structures showing Ar⁺ sputtering-related defects.